

<<表面形貌的光学测量>>

图书基本信息

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内容概要

本书介绍了表面形貌测量领域中一系列国际标准规范。
复杂的准则都是基于新的测量技术而产生的。
目前有很多用来测量表面形貌新的光学技术，每种方法都有其优点以及局限性。
本书既适用于业界及学术研究领域的工程人员，也适用于相关领域的研究生及高年级本科生。

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